

IN THE CLAIMS

1. (Currently amended) A ~~[[m]]ethod Method~~ for positioning of a substrate and for contacting of a test object with the following steps:

- a) putting the substrate with at least one test object on a holder;
- b) positioning the substrate relative to an optical axis of a test apparatus with a positioning activity;
- c) positioning the contact unit relative to the optical axis, whereby the contact unit is positioned independent of the positioning activity of the substrate;
- d) contacting of at least one contact assembly of the test object with the contact unit.

2.(Currently amended) The ~~[[m]]ethod of Method according to~~ claim 1, where~~[[in]]~~ ~~whereby~~ during contacting of the contact unit with the at least one contact assembly of the test object at least two contact pins of the contact unit are contacted with contact pads of the at least one contact assembly, and whereby for contacting the contact pins of the contact unit are not moved relative to each other.

3. (Currently amended) The ~~[[m]]ethod of Method according to any of the preceding claims 1,~~ where~~[[in]]~~ ~~whereby~~ the contact unit is positioned with an own drive.

4. (Currently amended) The ~~[[m]]ethod of Method according to any of the preceding claims 1,~~ where~~[[in]]~~ ~~whereby~~ the positioning steps (b, c, respectively) comprise a movement perpendicular to the optical axis of at least 5 cm, preferably of at least 20 cm.

5. (Currently amended) The ~~[[m]]ethod of Method according to any of the preceding claims 1,~~ where~~[[in]] whereby~~ the steps b) to d) are repeated several times during testing of a substrate, preferably at least between the testing of each test object.

6. (Currently amended) A ~~[[m]]ethod Method~~ for testing of a substrate with several test objects with a test apparatus, comprising the following steps:

- putting the substrate on a holder;
- contacting of a first test object with a contact unit;
- positioning of the substrate so that a first area of the first test object lies in a test range of the test apparatus;
- testing of the first area of the test object;
- displacing the substrate so that at least a further area of the first test object lies in the test range of the test apparatus;
- displacing the contact unit so that the position of the contact unit is essentially unchanged with respect to the first test object;
- testing of the further area of the test object;
- displacing the contact unit and the substrate relative to each other so that a further test object can be contacted.

7. (Currently amended) The ~~[[m]]ethod of Method according to claim 6,~~ where~~[[in]] whereby~~ the contact unit is displaced by tracking.

8. (Currently amended) The ~~[[m]]ethod of Method according to claim 6,~~ where~~[[in]] whereby~~ the contact unit is displaced by carrying along.

9. (Currently amended) ~~The [[m]]ethod Method according to any~~ of claim 6 to 8, where[[in]] ~~whereby~~ the contact unit is displaced as long as a contact to the substrate is present.

10. (Currently amended) ~~The [[m]]ethod Method according to any~~ of claim 6 to 9, where[[in]] ~~whereby~~ the test range is scanned by a beam deflection of a corpuscular beam in two directions.

11. (Currently amended) ~~The [[m]]ethod Method according to any~~ of claim 6 to 9, where[[in]] ~~whereby~~ the test range is scanned by a beam deflection of a corpuscular beam in one direction and a substrate movement in another direction.

12. (Currently amended) ~~The [[m]]ethod Method according to any~~ of claim 6 to 44, where[[in]] ~~whereby~~ the contact unit is displaced as long as no contact to the substrate is present.

13. (Currently amended) ~~The [[m]]ethod Method according to any~~ of claim 6 to 42, where[[in]] ~~whereby~~ the contact unit is adapted to different forms of test objects.

14. (Currently amended) ~~The [[m]]ethod Method according to any~~ of claim 6 to 43, where[[in]] ~~whereby~~ the testing is conducted by scanning of the test range with a corpuscular beam and measurement of the second area electrons.

15. (Currently amended) ~~The [[m]]ethod Method according to any~~ of claim 6 to 44, where[[in]] ~~whereby~~ the testing is conducted by scanning of the test range

with a corpuscular beam and measurement of a signal fed through the contact unit.

16. (Currently amended) The ~~[[m]]ethod Method according to any of claim 6 to 15, where[[in]]~~ whereby before the testing a vacuum of smaller than $1 \cdot 10^{-3}$ mbar is generated.

17. (Currently amended) An ~~[[a]]pparatus Apparatus~~ for contacting for the test of at least one test object (304) on a substrate (140), comprising:

- a holder (130) for the substrate;
- displacement unit (132, 134) for the holder with a holder displacement range in x-direction and a holder displacement range in y-direction;
- a contact unit (150) for contacting of the at least one test object, whereby the contact unit is displaceable in x-direction and in y-direction, and the contact unit displacement range in x-direction and/or the contact unit displacement range in y-direction are smaller than the respective holder displacement range.

18. (Currently amended) The ~~[[a]]pparatus Apparatus according to~~ of claim 17, where[[in]] whereby the contact unit displacement range in x-direction and in y-direction is larger than a corresponding contact alignment displacement range (220, 222) of the contact unit.

19. (Currently amended) An ~~[[a]]pparatus Apparatus~~ for contacting for the test of at least one test object (304) on the substrate, whereby for the test a test apparatus with an optical axis (102) is used, comprising:

- a holder (130) for a substrate with at least one test object;

- a displacing unit for the holder;
- a contact unit (150) for contacting of the at least one test object, whereby the contact unit is displaceable and has essentially maximal the dimension of half of the holder dimension in one direction perpendicular to the optical axis.

20. (Currently amended) The ~~[[a]]pparatus Apparatus according to of claim~~ 19, where~~[[in]]~~ whereby the contact unit has essentially maximal the dimensions of half of the holder the dimensions in two directions perpendicular to the optical axis.

21. (Currently amended) An ~~[[a]]pparatus Apparatus~~ for contacting for the test of at least one test object with a substrate (140), whereby for the test a test apparatus with an optical axis (102) is used, comprising:

- a holder (130) for the substrate displaceable with respect to the optical axis (102);
- a displaceable contact unit (150),

whereby the contact unit is displaceable during the test of the substrate with respect to the optical axis and with respect to the holder.

22. (Currently amended) The ~~[[a]]pparatus Apparatus according to any of claim~~ 17 ~~to 21~~, where~~[[in]]~~ whereby the contact unit is displaceable by at least 5 cm, preferably by at least 20 cm.

23. (Currently amended) The ~~[[a]]pparatus Apparatus according to any of claim~~ 17 ~~to 22~~, where~~[[in]]~~ whereby the contact unit has dimensions, so that no area to be tested of the test object to be tested is covered by the contact unit.

24. (Currently amended) The ~~[[a]]pparatus Apparatus according to any~~ of claim 17 ~~to 23~~, where~~[[in]]~~ ~~whereby~~ the contact unit has a size which is larger than the test range (302) during testing.

25. (Currently amended) The ~~[[a]]pparatus Apparatus according to any~~ of claim 17 ~~to 24~~, where~~[[in]]~~ ~~whereby~~ the contact unit is connected with a displacing unit with a drive (152) for displacement relative to the optical axis.

26. (Currently amended) The ~~[[a]]pparatus Apparatus according to any~~ of claim 17 ~~to 25~~, where~~[[in]]~~ ~~whereby~~ a synchronization unit (160) exists, which synchronizes the displacing unit of the contact unit and of the holder.

27. (Currently amended) The ~~[[a]]pparatus Apparatus according to any~~ of claim 17 ~~to 26~~, where~~[[in]]~~ ~~whereby~~ the contact unit has contact pins for contacting.

28. (Currently amended) The ~~[[a]]pparatus of Apparatus according to claim 27~~, where~~[[in]]~~ ~~whereby~~ the contact pins for contacting with the contact unit (150) are not movable relative to each other during the testing of a substrate.

29. (Currently amended) The ~~[[a]]pparatus of Apparatus according to claim 27~~, where~~[[in]]~~ ~~whereby~~ the contact pins for contacting with the contact unit (150) are not movable relative to each other.

30. (Currently amended) The ~~[[a]]pparatus Apparatus according to any~~ of claim 17 ~~to 29~~, where~~[[in]]~~ ~~whereby~~ the contact unit (150) is adjustable on different sizes of test objects.

31. (Currently amended) The ~~[[a]]pparatus Apparatus according to any of claim 17 to 30, where[[in]] whereby~~ the test object is at least one display (304) with a contact assembly (200).

32. (Currently amended) The ~~[[a]]pparatus Apparatus according to any of claim 17 to 31, where[[in]] whereby~~ the apparatus is adapted to be used in a vacuum.

33. (Currently amended) The ~~[[a]]pparatus Apparatus according to any of claim 17 to 32, where[[in]] whereby~~ the contact unit is connected with an external control (162) and/or a measurement unit (162).

34. (Currently amended) The ~~[[a]]pparatus Apparatus according to any of claim 17 to 32, where[[in]] whereby~~ the contact unit is displaceable during the testing of the substrate.

35. (Currently amended) A ~~[[t]]est Test~~ system comprising:

an evacuable test chamber (108);

a corpuscular beam column (104) with an optical axis (102); and

an apparatus for contacting for the test of at least one test object on a substrate ~~according to any of claim 17 to 34.~~

36. (Currently amended) A ~~[[m]]ethod Method~~ for testing of a substrate with several test object, where[[in]] ~~whereby~~ for testing a test apparatus with an optical axis is used, comprising the following steps:

- putting the substrate a holder;
- contacting of a first test object with a contact unit;

- positioning of the substrate and the optical axis relative to each other so that a first area of the first test object lies in a test range of the test apparatus.
- testing of the first area of the test object;
- displacing the substrate and the optical axis relative to each other so that at least a further area of the first test object lies in the test range of the test apparatus;
- testing of the further area of the test object;
- displacing the contact unit and the substrate relative to each other, so that a further test object can be contacted.

37. (Currently amended) The ~~[[m]]ethod of Method according to~~ claim 36, where~~[[in]]~~ ~~whereby~~ the optical axis of the test apparatus is positioned relative to the substrate and the contact unit is displaced relative to substrate.

38. (Currently amended) The ~~[[m]]ethod Method according to any of claim 36 to 37, where~~~~[[in]]~~ ~~whereby~~ the test range is detected with a light optical system.

39. (Currently amended) The ~~[[m]]ethod Method according to any of claim 36 to 37, where~~~~[[in]]~~ ~~whereby~~ the contact unit is adapted to different forms of the test objects.

40. (Currently amended) An ~~[[a]]pparatus Apparatus~~ for contacting for the test of at least one test object (301) on the substrate, whereby for the test a test apparatus with an optical axis is used, comprising:

- a holder ~~(130)~~ for substrate with at least one test object;
- a displacing unit for displacement of the optical axis ~~(102)~~;

- a contact unit (50) for contacting of the at least one test object, whereby the contact unit is displaceable relative to the optical axis and independent thereof relative to the holder and has essentially maximal the dimension of a half of the holder dimension in one direction perpendicular to an optical axis.

41. (Currently amended) The ~~[[a]]pparatus of Apparatus according to~~ claim 40, where~~[[in]]~~ whereby the contact unit has essentially maximal the dimension of half of the holder dimension in two directions perpendicular to an optical axis.

42. (Currently amended) An ~~[[a]]pparatus Apparatus~~ for contacting for the test of at least one test object on the substrate (140), whereby for the test a test apparatus with an optical axis (102) is used, comprising:

- an optical axis (102) displaceable with respect to the holder (130) for the substrate;
- a displaceable contact unit (150),

whereby the contact unit is displaceable during the testing of the substrate with respect to the optical axis and with respect to the holder.

43. (Currently amended) The ~~[[a]]pparatus Apparatus according to any of claims 40 to 42,~~ where~~[[in]]~~ whereby the contact unit is displaceable by at least 50 mm, preferably by at least 200 mm.

44. (Currently amended) The ~~[[a]]pparatus Apparatus according to any of claims 40 to 43,~~ where~~[[in]]~~ whereby the contact unit has dimensions so that no area to be tested of the test object is covered by the contact unit.

45. (Currently amended) The ~~[[a]]pparatus Apparatus according to~~ any of claims 40 to 44, where~~[[in]]~~ ~~whereby~~ the contact unit has a size larger than the test range (302) during testing.

46. (Currently amended) The ~~[[a]]pparatus Apparatus according to~~ any of claims 40 to 45, where~~[[in]]~~ ~~whereby~~ the contact unit is connected with a displacing unit with a drive (152) for displacement relative to the optical axis.

47. (Currently amended) The ~~[[a]]pparatus Apparatus according to~~ any of claims 40 to 42, where~~[[in]]~~ ~~whereby~~ a synchronizing unit (160) exists, which synchronizes the displacing unit of the contact unit and a further displacing unit.

48. (Currently amended) The ~~[[a]]pparatus of Apparatus according to~~ claim 47, where~~[[in]]~~ ~~whereby~~ the further displacing unit is a displacing unit for the optical axis.

49. (Currently amended) The ~~[[a]]pparatus Apparatus according to~~ any of claims 40 to 48, where~~[[in]]~~ ~~whereby~~ the contact unit has contact pins for contacting.

50. (Currently amended) The ~~[[a]]pparatus Apparatus according to~~ any of claims 40 to 49, where~~[[in]]~~ ~~whereby~~ the contact unit (150) is adaptable to different sizes of test objects.

51. (Currently amended) The ~~[[a]]pparatus Apparatus according to~~ any of claims 40 to 50, where~~[[in]]~~ ~~whereby~~ the test object is at least one display (304) with a contact arrangement (200).

52. (Currently amended) ~~The [[a]]pparatus Apparatus according to any of claims 40 to 51, where[[in]] whereby~~ the contact unit is connected with an external control (162) and/or a measurement unit (162).